

Intel Silicon & Manufacturing Update

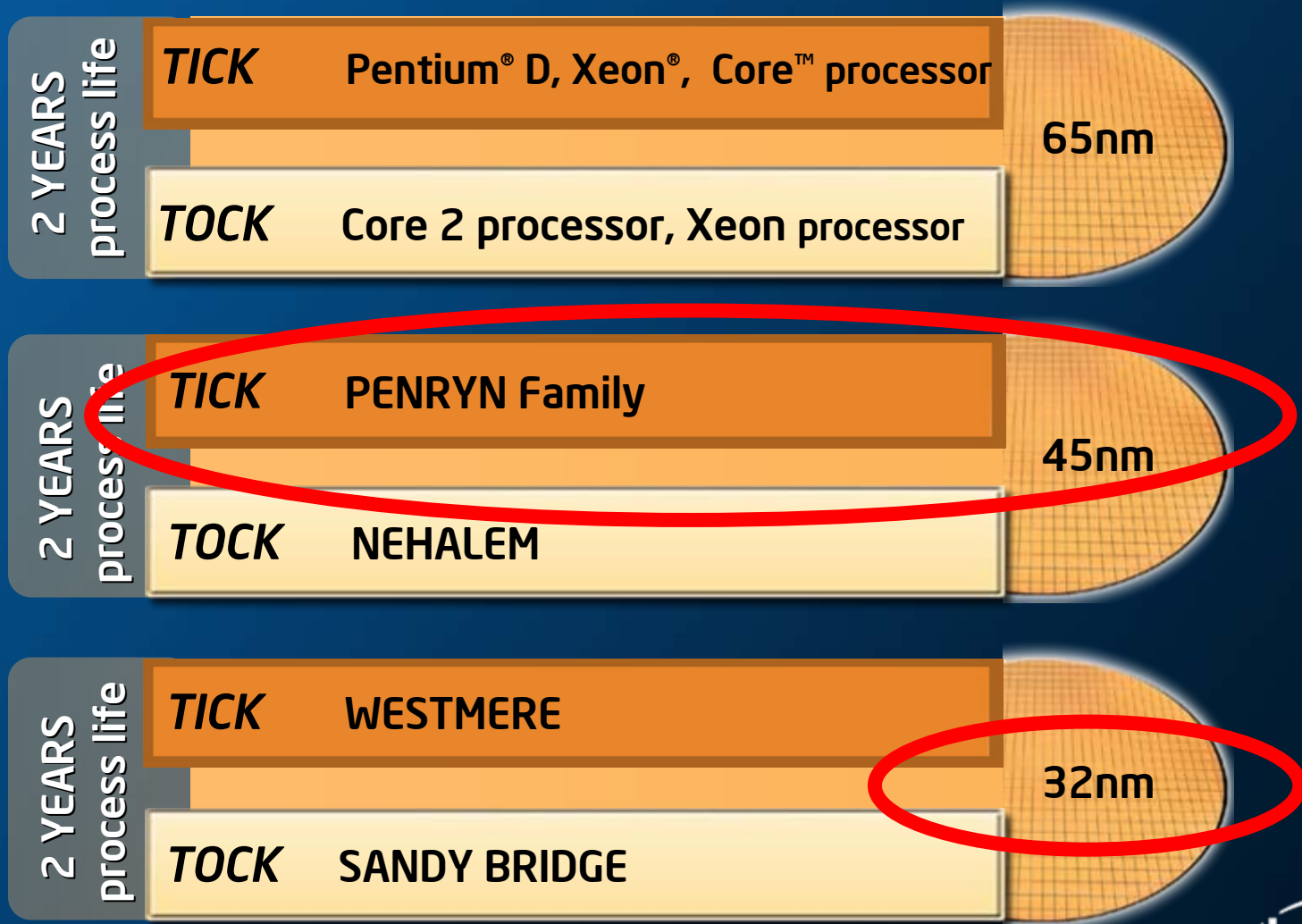
The background image shows a long, brightly lit semiconductor manufacturing facility. A worker in a white cleanroom suit is walking away from the camera down a central aisle. On either side of the aisle are rows of large, complex industrial machines used for chip production. The ceiling is high with visible structural beams and lighting fixtures. Exit signs are visible on the ceiling.

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September 18, 2007

Alternating Process and Product Introductions for Sustained Leadership



New process generation
New product architecture



45nm Status

- 1st generation revolutionary high-k + metal gate transistors for improved performance and reduced leakage power
- Working “Penryn” microprocessors were first demonstrated in January '07 and “Silverthorne” microprocessors in April '07
- Intel’s 45nm processors are 100% lead-free
- Intel 45nm CPUs will convert to halogen-free packaging technology by the end of 2008
- Intel’s 45 nm process technology will be described in more detail at the International Electron Devices Meeting (Dec 10-12, 2007)

45nm High-k -- Fundamental, Game-Changing Technology 

High-k + Metal Gate Delivers True Performance per Watt Improvement

#1: Power Reduction (energy efficient computing)

1/10th gate oxide leakage

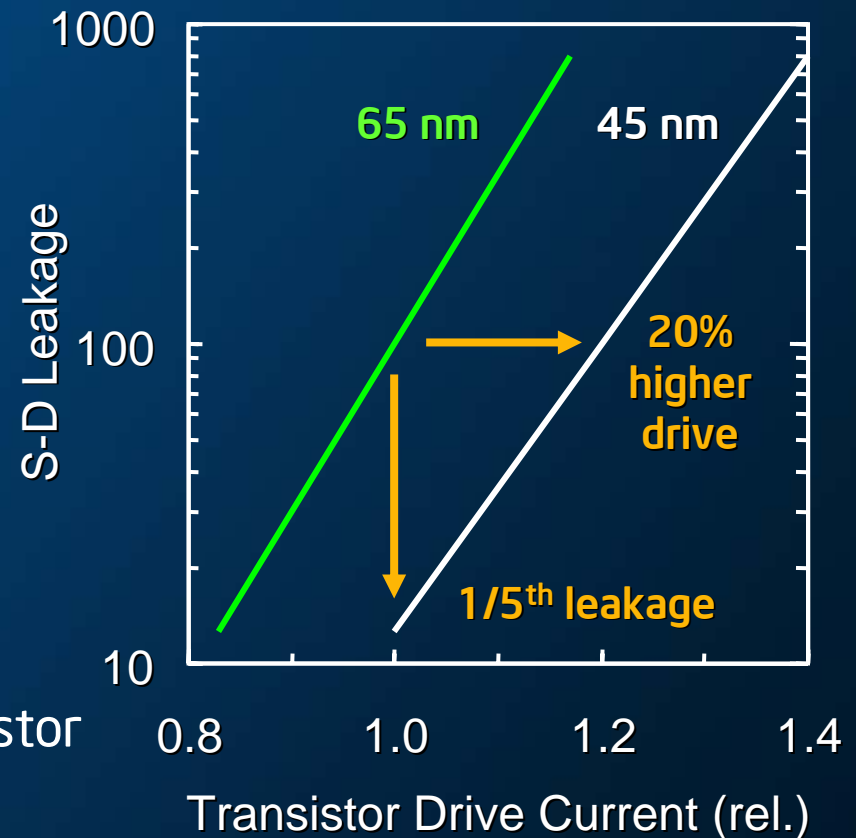
1/5th S-D leakage

#2: Performance Increase

20% higher drive current

#3: Scaling

Higher drive enables smaller transistor width for same drive strength



45nm Manufacturing Readiness & Operational Leadership

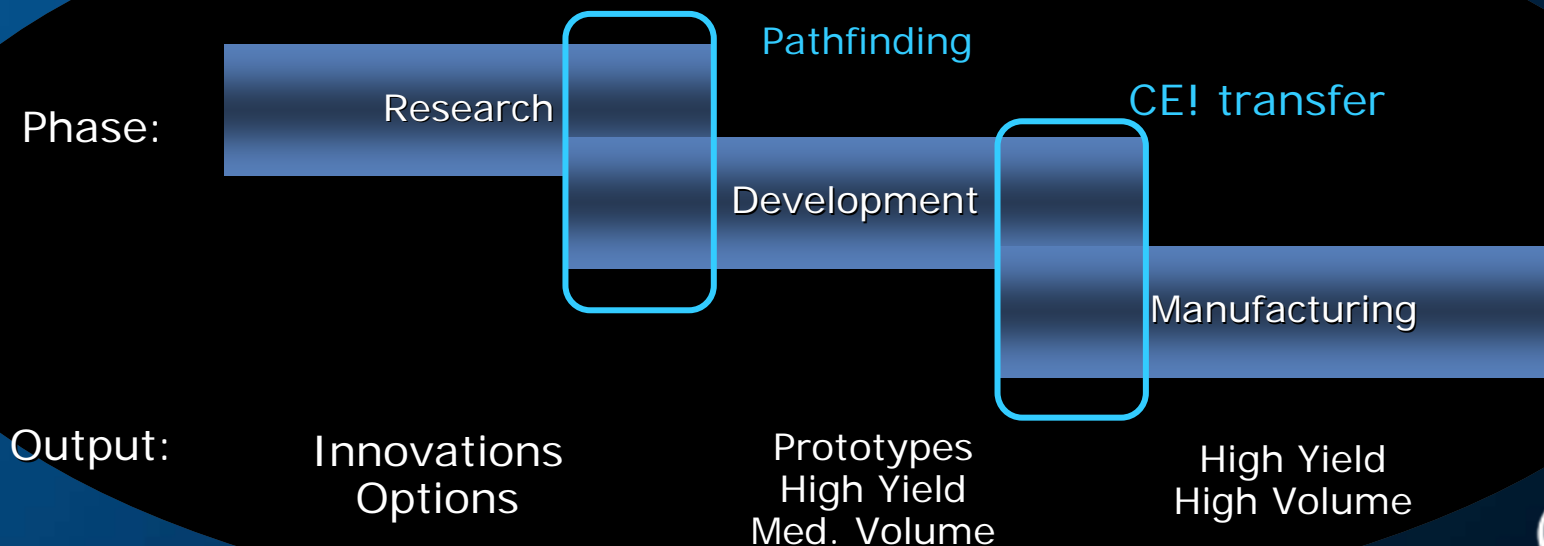


We Have a Well-Honed, *Unique* R-D-M Method

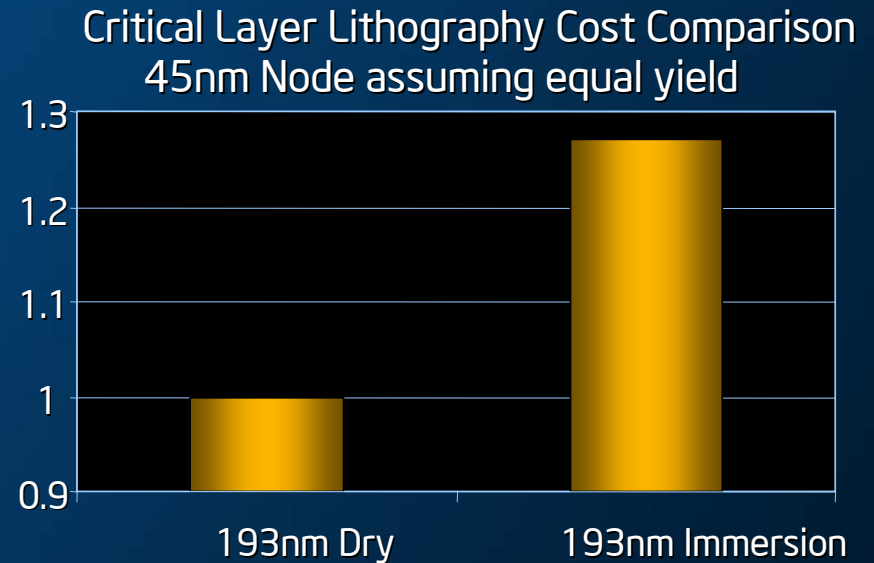
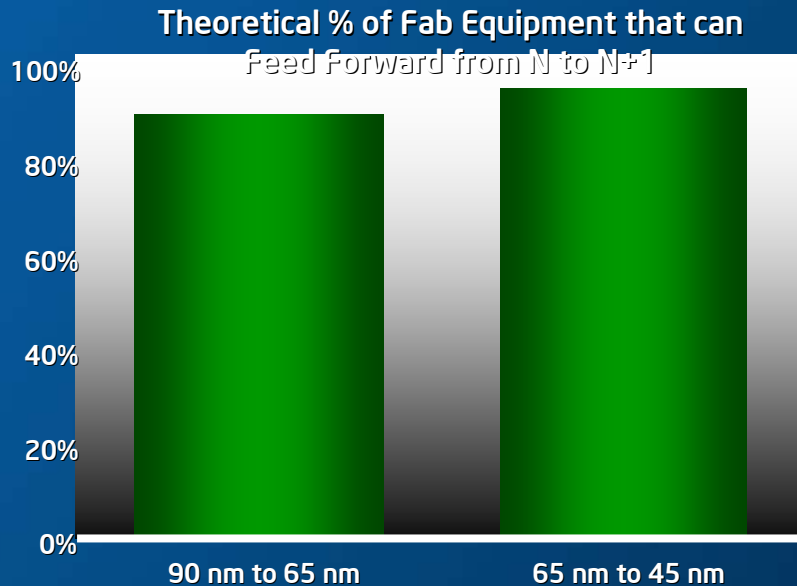
Traditional R-D-M Method:



Intel's R-D-M Method:



Capital Reuse



Capital Reuse Enables Predictable Ramps

45nm Factory Network

D1D Oregon - 2H '07



Fab 32 Arizona - 2H '07



Fab 28 Israel - 1H '08



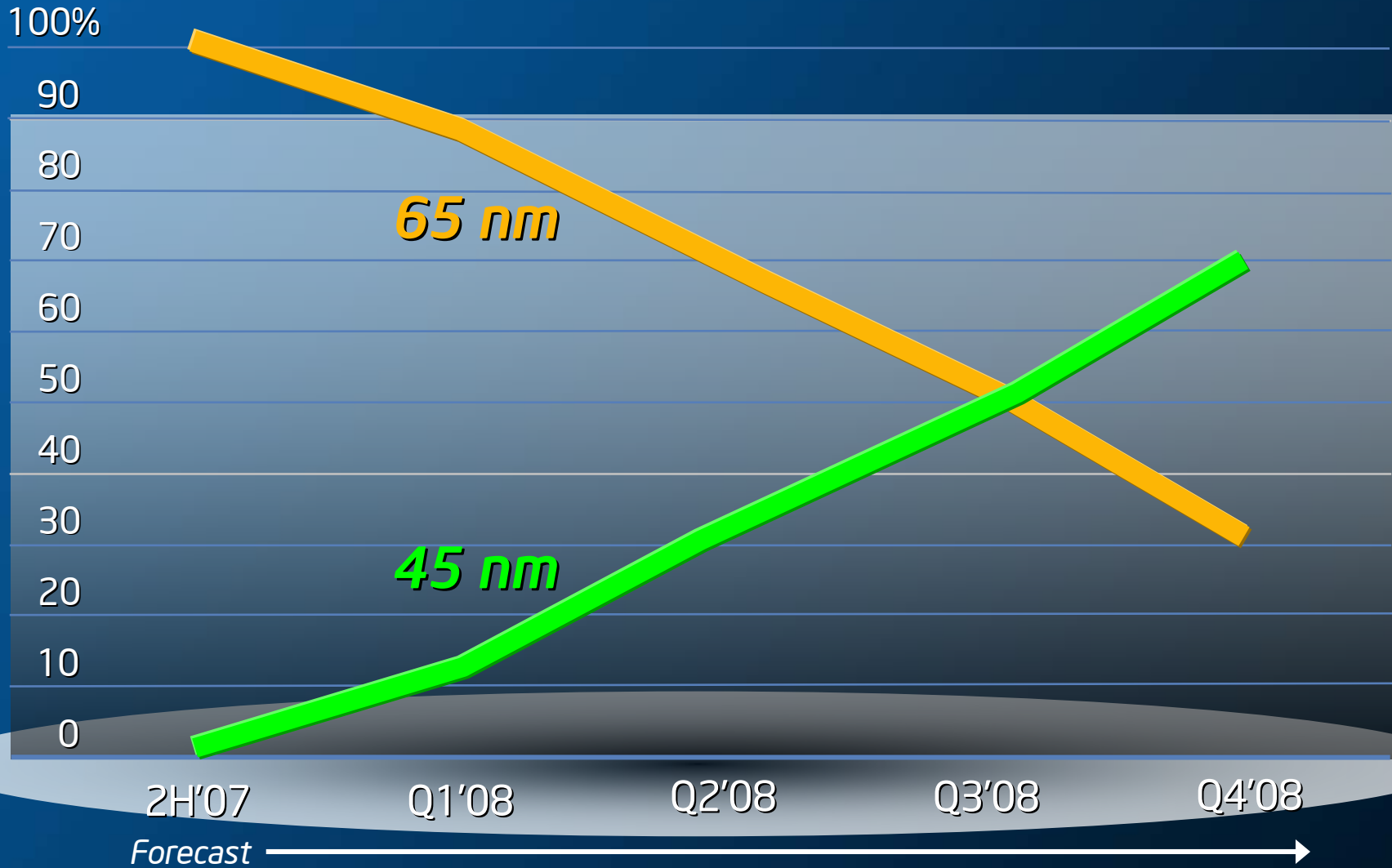
Fab 11X New Mexico - 2H '08



Source: Intel



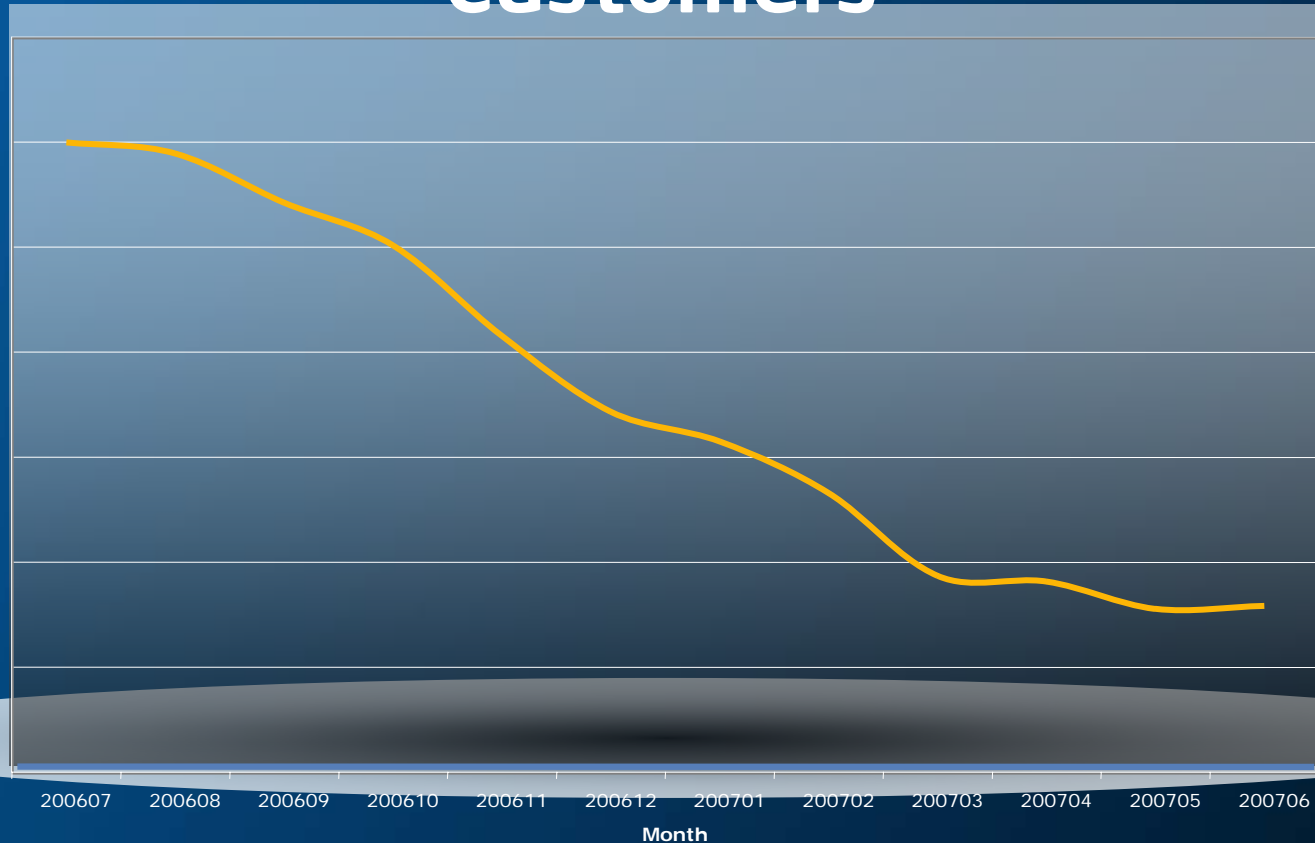
CPU Shipments (65nm vs. 45nm)



Source: Intel Internal



Improvements in Factory Throughput Time Increase Agility & Ability to Serve our Customers

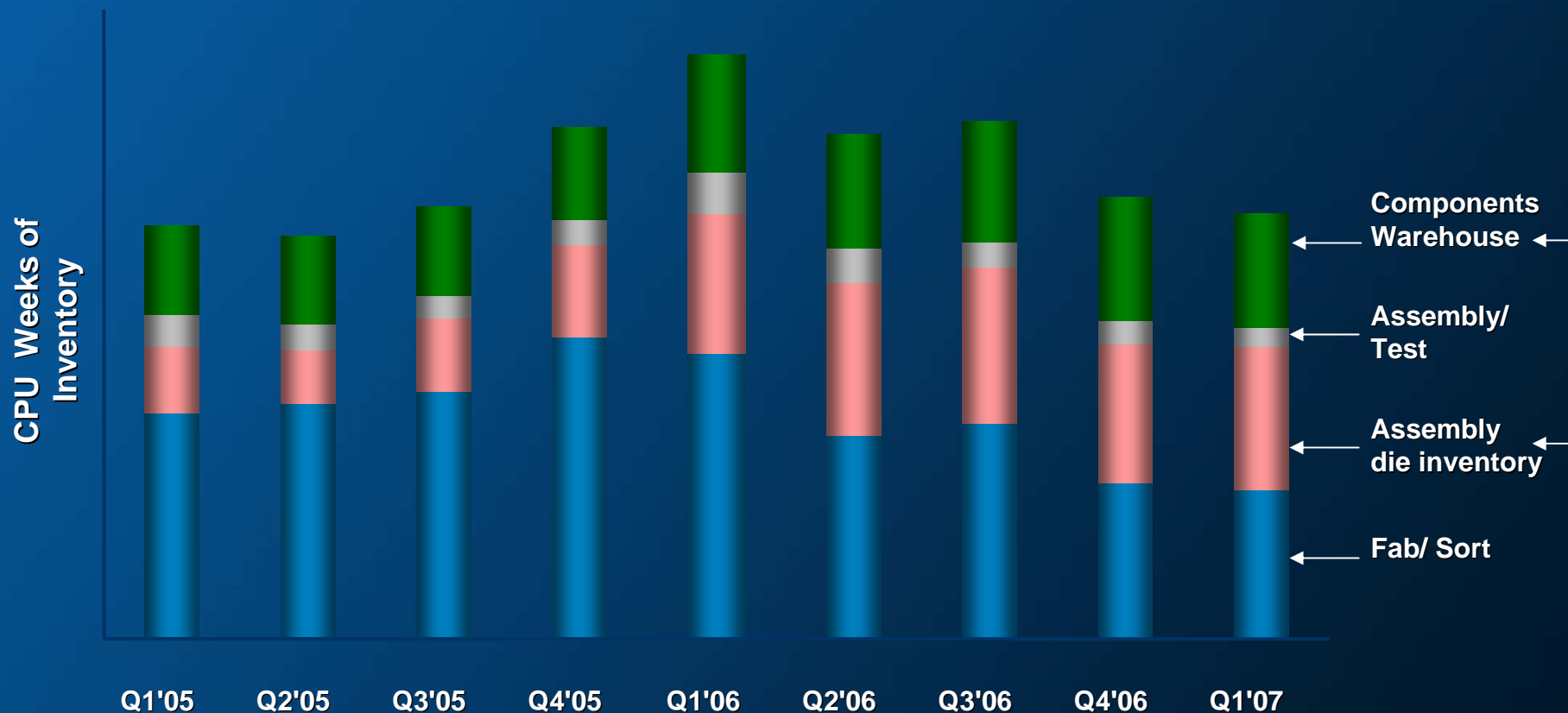


50% Improvement in throughput time

Source: Intel Internal



Improved Manufacturing Throughput Time Drives Inventory Reductions



- Fab and Assembly inventories cut by 50%
- Die and finished goods remain at desired levels

Note: Quarterly numbers represents the last month of each quarter



Conclusions

- Sustainable Process Technology Leadership – 2 year cadence
- Well-Honed, Unique R-D-M Method
 - Copy Exactly! – cornerstone of matched yields, predictable ramps
 - 45nm Yields – on track
 - 45nm Mfg Readiness – on track
- 45nm Crossover in 2H 2008 – on track
- Continuous improvements Leading to System wide gains
 - Throughput times, Response to Customer Orders
 - Inventory Reduction
- Intel's 45nm Manufacturing - > 1 yr ahead of the competition

*Most **Cost Effective, Smallest, Fastest, Healthiest Products** in our Customers' Hands...**Earlier** than Anyone Else!*

Beyond 45nm ...

Intel First to Demonstrate Working
32 nm SRAM + Logic Chips



Intel's Logic Technology Evolution

Process Name	<u>P1264</u>	<u>P1266</u>	<u>P1268</u>	<u>P1270</u>
Lithography	65 nm	45 nm	32 nm	22 nm
1 st Production	2005	2007	2009	2011

Moore's Law Continues!

Intel continues to develop a new technology generation every 2 years



What are We Announcing Today?

- Functional 32nm 291 Mbit SRAM chips
 - Each chip with >1.9 billion transistors
- Intel first to reach this critical 32nm development milestone
- 32nm SRAM chip memory cell size of 0.182 μm^2
 - ~1/2 the 45nm cell
- Uses 2nd generation high-k + metal gate transistors
- Optimized Patterning:
 - 193nm immersion lithography for critical masking layers
 - 193nm dry or 248nm dry lithography for less-critical layers
- Intel is on track to ramp 32nm logic technology in 2009



Intel SRAM Test Chips



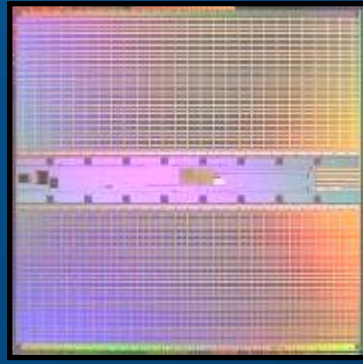
90 nm Process

1.0 μm^2 cell

50 Mbit

109 mm^2

February '02



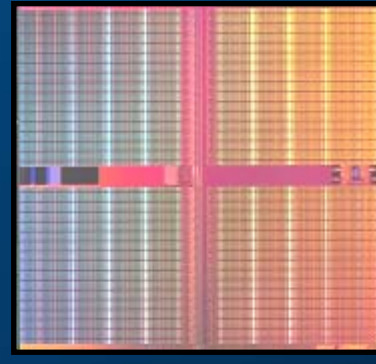
65 nm Process

0.57 μm^2 cell

70 Mbit

110 mm^2

April '04



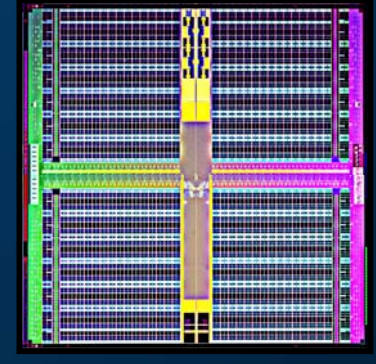
45 nm Process

0.346 μm^2 cell

153 Mbit

119 mm^2

January '06



32 nm Process

0.182 μm^2 cell

291 Mbit

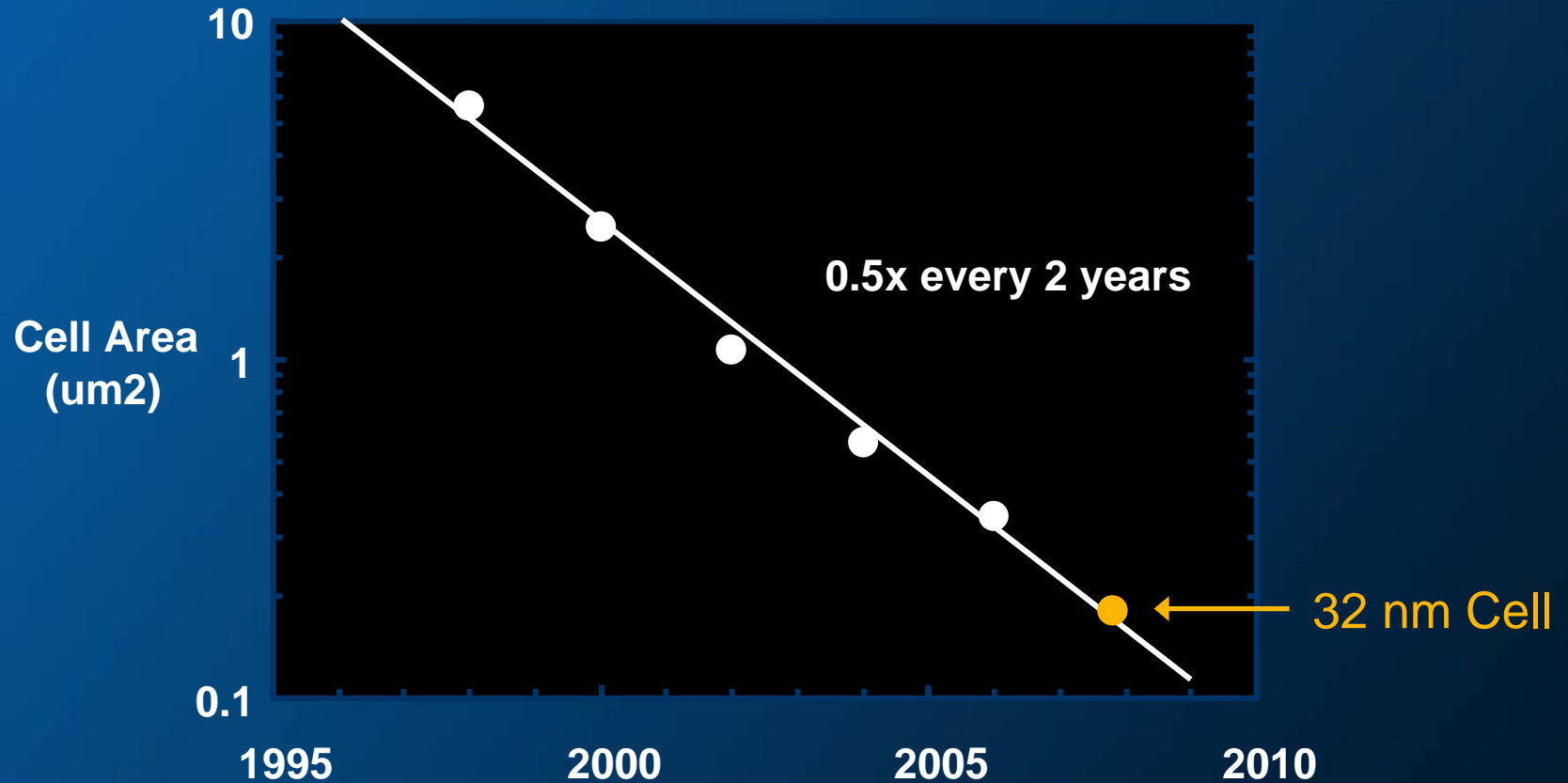
118 mm^2

September '07

New SRAM test vehicle developed every 2 years to lead development of logic technologies



Intel SRAM Cell Size Trend



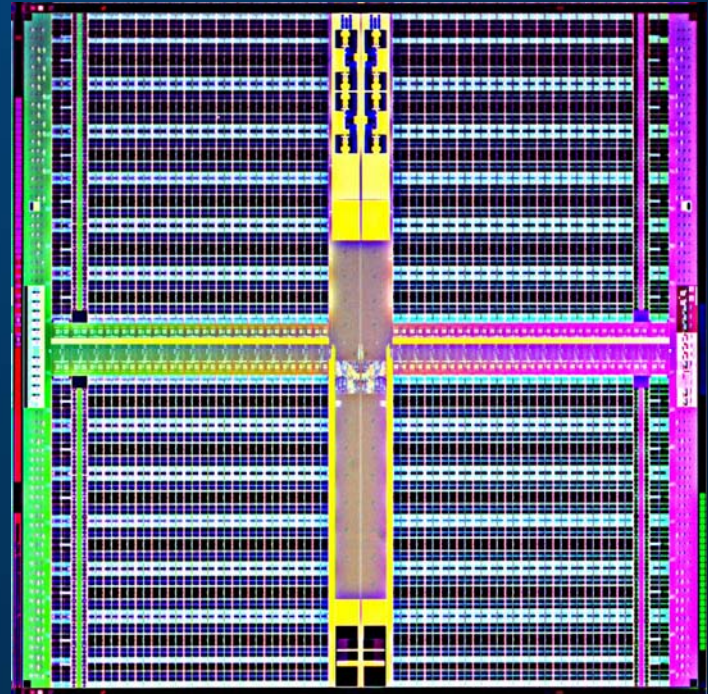
The smaller the SRAM cell, the more transistors that can be packed on a chip and utilized for more features

Transistor density continues to double every 2 years



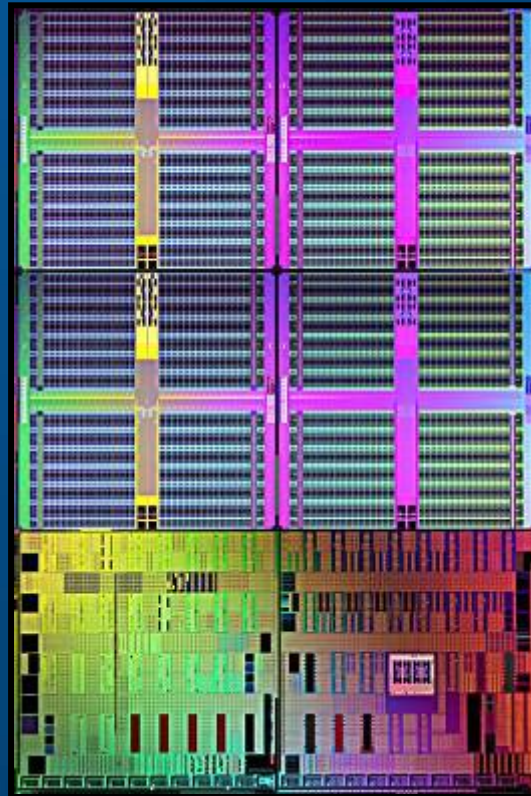
32 nm SRAM Chip

- 0.182 μm^2 cell size
- 291 Mbit, >1.9 billion transistors
- 118 mm^2 chip size
- 2nd gen. high-k + metal gate transistors
- 193 nm immersion lithography on critical layers
- 193 nm dry or 248 nm dry litho on less critical layers
- Functional silicon in Sept '07



32 nm SRAM test vehicle includes all transistor and interconnect features to be used on 32 nm microprocessors

32 nm Test Chip



291 Mbit SRAM

SRAM array

PROM array

High speed register file

High speed I/O circuits

High frequency PLL/Clock

Discrete test structures

32 nm design-for-manufacturability (DFM) test chip includes
SRAM and Logic circuits for microprocessors

DFM allows early co-optimization of process and design



Summary

- Intel's 32 nm logic technology has been demonstrated on functional 291 Mbit SRAM chips with >1.9 billion transistors
- These SRAM test chips exercise all transistor and interconnect features to be used on 32 nm microprocessors, including 2nd generation high-k + metal gate transistors
- 32 nm technology will provide significant density, performance and power improvements over today's 45 nm technology
- No other company has demonstrated this level of progress on its 32 nm process
- Intel is on track for 32 nm ramp in 2009

